10-07-03

DAC/$

Docket No. 2862/D01/Y01/SYNX/SYNX/JB

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Mail Stop Petition
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Re: Inventor: Ilya Perlov (Deceased), Eugene Gantvarg and Victor Belitsky
Title: APPARATUS FOR STORING AND MOVING A CASSETTE
Serial No.: 09/918,198
Filed: July 30, 2001
Examiner: James W. Keenan
Group Art Unit: 3652

Transmitted herewith is:

X Petition for Withdrawal of Abandonment with:
X Previously filed RCE TRANSMITTAL (filed June 5, 2003)
X Previously filed AMENDMENT (filed June 5, 2003)
X Previously filed EXTENSION OF TIME (filed June 5, 2003)
X Return Receipt Postcards

FEE CALCULATION					
Total Claims	N/A	- 20 =	-0-	X $18.00	$0.00
Independent Claims	N/A	- 3 =	-0-	X $78.00	$0.00
Basic Filing Fee				$760.00	$0.00
TOTAL FEES					$0.00

XX The Commissioner is hereby authorized to charge $130.00 to Deposit Account No. 04-1696.

XX The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. **04-1696**. A duplicate copy of this transmittal is enclosed.

XX Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Mail Stop Petition, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Express Mail Receipt No. EV158464566US

Date of Deposit: October 6, 2003

Signature: _____

Respectfully submitted,

Brian M. Dugan
Registration No. 41,720
(914) 332-9081

Express Mail Label No. EV158464566US

10/28/03
#10

Practitioner's Docket No. 2862/D01/Y01/SYNX/SYNX/JB *PATENT*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Ilya Perlov (Deceased), Eugene Gantvarg and Victor Belitsky
Application No.: 09/918,198 Group No.: 3652
Filed: July 30, 2001 Examiner: James W. Keenan
For: APPARATUS FOR STORING AND MOVING A CASSETTE

Mail Stop Petition
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PETITION FOR WITHDRAWAL OF ABANDONMENT

PETITION

1. Applicants petition that the abandonment set forth in the notice mailed by the Office on July 30, 2003 be withdrawn.

SUBMISSION

2. Submitted herewith is:

   A copy of the complete Request for Continued Examination (RCE) Transmittal, Amendment and Request for Extension of Time previously filed; and a copy of the fax confirmation sheet confirming receipt of the same by the US Patent & Trademark Office.

3. Please proceed with further examination of this application on the basis of:

   The attached copy of the papers originally filed.

PETITION FEE

4. The petition fee (37 C.F.R. 1.17(h)) is paid as follows:

   Authorization to charge deposit account no. 04-1696 in the sum of $130.

Express Mail Label No. EV158464566US

REQUEST FOR REFUND OF PETITION FEE

5. As no defect exists in applicant's previous submission, a refund of the petition fee submitted herewith is respectfully requested.

REQUEST FOR WITHDRAWAL OF ABANDONMENT

6. Acknowledgment of the active status of this application is respectfully requested.

SIGNATURE OF PRACTITIONER

Reg. No. 41,720
Tel. No.: (914) 332-9081

Brian M. Dugan
Dugan & Dugan, PC
18 John Street
Tarrytown, NY 10591

DATED: October 6, 2003

2862/D01/Y01/SYNX/SYNX/BG

#14
P. allen
07/21/04

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s)	:	Ilya Perlov, Eugene Gantvarg and Victor Belitsky
Serial No.	:	09/918,198
Filed	:	July 30, 2001
For	:	APPARATUS FOR STORING AND MOVING A CASSETTE
Examiner	:	James W. Keenan
Group Art Unit	:	3652

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

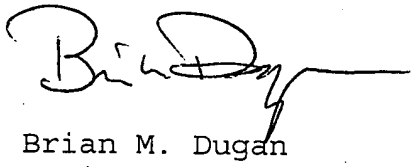
REQUEST FOR EXTENSION OF TIME
PURSUANT TO 37 CFR § 1.17 (a) (3)

Sir:

Applicants respectfully request a three-month extension of time in which to respond to the Examiner's Office Action mailed December 5, 2002, in which a three-month period for response was set to expire on March 5, 2003. After granting the request for a three-month extension of time, the response period will expire on June 5, 2003.

Please charge Deposit Account No. 04-1696 in the amount of $920.00 to cover the three month extension of time. No other fees are believed necessary, however if additional fees are required please charge deposit account No. 04-1696.

Respectfully submitted,



Brian M. Dugan
Registration No. 41,720

Dated: June 5, 2003
Tarrytown, New York

#15 P. allen 07/16/04

PTO/SB/30 (05-03)
Approved for use through 4/30/2003 OMB 0651-0031
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REQUEST FOR CONTINUED EXAMINATION (RCE) TRANSMITTAL

Address to:
Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Application Number	09/918,198
Filing Date	July 30, 2001
First Named Inventor	Ilya Perlov
Art Unit	3652
Examiner Name	James W. Keenan
Attorney Docket Number	2862/D01/Y01/ATD/ATD/BG

This is a Request for Continued Examination (RCE) under 37 CFR 1.114 of the above-identified application
Request for Continued Examination (RCE) practice under 37 CFR 1.114 does not apply to any utility or plant application filed prior to June 8, 1995, or to any design application. See Instruction Sheet for RCEs (not to be submitted to the USPTO) on page 2.

1. Submission required under 37 CFR 1.114 Note: If the RCE is proper, any previously filed unentered and amendments enclosed with the RCE will be entered in the order in which they were filed unless applicant instructs otherwise. If applicant does not wish to have any previously filed unentered amendment(s) entered, applicant must request non-entry of such

a. ☐ Previously submitted. If a final Office action is outstanding, any amendments filed after the final Office action may be considered as a submission even if this box is not checked.
   i. ☐ Consider the arguments in the Appeal Brief or Reply Brief previously filed on _____
   ii. ☐ Other _____

b. ☒ Enclosed
   i. ☒ Amendment/Reply
   ii. ☐ Affidavit(s)/Declaration(s)
   iii. ☐ Information Disclosure Statement (IDS)
   iv. ☒ Other **Request for 3 Month Extension of Time**

2. Miscellaneous
a. ☐ Suspension of action on the above-identified application is requested under 37 CFR 1.103(c) for a period of _____ months (Period of suspension shall not exceed 3 months; Fee under 37 CFR 1.17(i) required)
b. ☐ Other

3. Fees The RCE fee under 37 CFR 1.17(e) is required by 37 CFR 1.114 when the RCE is filed.
a. ☒ The Director is hereby authorized to charge the following fees, or credit any overpayments, to Deposit Account No. 04-1696
   i. ☒ RCE fee required under 37 CFR 1.17(e)
   ii. ☒ Extension of time fee (37 CFR 1.136 and 1.17)
   iii. ☐ Other _____
b. ☐ Check in the amount of $ _____ enclosed
c. ☐ Payment by credit card (Form PTO-2038 enclosed)
WARNING: Information on this form may become public. Credit card information should not be included on this form. Provide credit card information and authorization on PTO-2038.

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT REQUIRED

Name (Print / Type)	Brian M. Dugan	*Registration No. (Attorney / Agent)*	41,720
Signature		*Date*	06/05/2003

CERTIFICATE OF MAILING OR TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop RCE, Commissioner For Patents, P.O. Box 1450, Alexandria, VA 22313-1450 or facsimile transmitted to the U.S. Patent andTrademark Office on the date shown below.

Name (Print / Type)	Brian M. Dugan		
Signature		*Date*	06/05/2003

This collection of information is required by 37 CFR 1.8. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 12 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing the burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. **SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.**

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.

VALERIE G. DUGAN
BRIAN M. DUGAN, PH.D.

DUGAN & DUGAN, PC
PATENTS, TRADEMARKS & COPYRIGHTS
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FACSIMILE COVER SHEET

June 5, 2003

PLEASE DELIVER THE ATTACHED MESSAGE TO:

Examiner James W. Keenan — Phone No.: (703) 308-2559
Fax No.: (703) 305-7687

From: Brian M. Dugan

Our File No.: 2862/D01/Y01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants	:	Ilya Perlov, Eugene Gantvarg and Victor Belitsky
Serial No.	:	09/918,198
Filed	:	July 30, 2001
For	:	APPARATUS FOR STORING AND MOVING A CASSETTE
Examiner	:	James W. Keenan
Group Art Unit	:	3652

TOTAL NUMBER OF PAGES INCLUDING THIS PAGE: 18

* * *

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* * *

PATENTS
2862/D01/Y01/SYNX/SYNX/BG

66/D
P. Cullen
07/24/04

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants	:	Ilya Perlov, Eugene Gantvarg and Victor Belitsky
Serial No.	:	09/918,198
Filed	:	July 30, 2001
For	:	APPARATUS FOR STORING AND MOVING A CASSETTE
Examiner	:	James W. Keenan
Group Art Unit	:	3652

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Examiner's Advisory Action dated March 13, 2003, and in conjunction with the Request for Continuing Examination submitted herewith, it is requested that the subject application be amended as follows.

Certificate of Mailing/Transmission (37 C.F.R. Section 1.8(a))
I hereby certify that, on the date shown below, this correspondence is being:
X transmitted by facsimile to the Patent and Trademark Office

Signature 6/5/03 Date

BRIAN M. DUGAN
(name of person certifying)

Respectfully submitted,

Brian M. Dugan
Registration No. 41,720

In the Claims:

Please cancel claims 1-3 and 5-21 without prejudice.

Please add new claims 22-54 as presented below.

23 22. An apparatus for storing wafer carriers, comprising:

a frame positionable on a cleanroom floor adjacent an interface wall separating a processing station from the cleanroom, the frame comprising a floor-mounting portion configured so as to extend along the interface wall at an elevation below that of a docking station located adjacent a docking port formed in the interface wall through which the processing station may receive and discharge substrates with a wafer carrier disposed on the docking station;

a plurality of wafer carrier storage shelves supported by the frame and aligned in a vertical column above the docking station; and

a wafer carrier mover adapted to carry a wafer carrier between a shelf of the plurality of wafer carrier storage shelves and the docking station, the wafer carrier mover including a support member adapted to be moved parallel to the interface wall, adjacent the plurality of wafer carrier storage shelves, and an end effector movably connected to the support member and configured to engage the wafer carrier, the wafer carrier mover being supported by the frame.

24 23. The apparatus of claim ~~22~~ 23, wherein the floor-mounting portion of the frame is further configured so as to substantially fit below the docking station.

25 24. The apparatus of claim ~~23~~ 23, wherein the frame further comprises at least one vertically-extending post extending

upward from the floor-mounting portion so as to support the plurality of wafer carrier storage shelves.

25. The apparatus of claim 22, wherein the frame has a rectangular aspect.

26. The apparatus of claim 25, wherein the frame has a rectangular aspect as viewed from above the frame.

27. The apparatus of claim 25, wherein the frame has a rectangular aspect as viewed from in front of the frame, looking toward the interface wall.

28. The apparatus of claim 22, wherein the frame is limited in length so as to fit in front of the processing station without extending in front of adjacent processing stations.

29. The apparatus of claim 22, wherein the floor-mounting portion of the frame comprises a horizontally-extending frame member configured to extend outward away from the interface wall so as to define a depth of the frame.

30. The apparatus of claim 29, wherein the frame is configured so as to contain the plurality of wafer carrier storage shelves within the depth of the frame.

31. The apparatus of claim 29, wherein the frame is configured so as to contain the end effector of the wafer carrier mover within the depth of the frame.

32. The apparatus of claim 29, wherein the frame is configured so as to contain wafer carriers stored on the

plurality of wafer carrier storage shelves within the depth of the frame.

34 33. The apparatus of claim 29 30, wherein the horizontally-extending frame member extends outward away from and perpendicular to the interface wall.

35 34. The apparatus of claim 22 23, wherein the floor-mounting portion extends parallel to the interface wall.

36 35. The apparatus of claim 22 23, wherein each of the plurality of wafer carrier storage shelves are positioned adjacent the interface wall.

37 36. The apparatus of claim 22 23, wherein the vertical column of wafer carrier storage shelves is positioned adjacent a vertical channel so as to permit movement of wafer carriers along the vertical column.

38 37. The apparatus of claim 36 37, wherein the wafer carrier mover is adapted to transport a wafer carrier to a selected storage shelf by moving the wafer carrier vertically through the vertical channel to position the wafer carrier adjacent the selected storage shelf and at an elevation above an elevation of the selected storage shelf, and horizontally to position the wafer carrier over the selected storage shelf.

39 38. The apparatus of claim 22 23, further comprising an interstation wafer carrier mover to transport a wafer carrier between one of the first plurality of shelves and a wafer carrier storage shelf of another wafer carrier storage apparatus.

Fig 12 Bonora ivo Fosnight

39. The apparatus of claim 38, wherein the interstation wafer carrier mover includes a support member movable in a path parallel to the interface wall and an end effector adapted to engage the wafer carrier, the end effector being vertically movable relative to the support member of the interstation wafer carrier mover.

40. The apparatus of claim 38, wherein the interstation wafer carrier mover further comprises a rotary mechanism adapted to move the wafer carrier through a curved path.

41. The apparatus of claim 40, wherein the rotary mechanism is adapted to move the wafer carrier through a curved path so as to permit the wafer carrier to be exchanged between the processing station and another processing station disposed on another side of a corner of the cleanroom.

42. The apparatus of claim 40, wherein the rotary mechanism is adapted to move the wafer carrier through a curved path so as to permit the wafer carrier to be exchanged between the processing station and another processing station disposed along another wall of the cleanroom opposite the interface wall.

43. In a semiconductor device processing system, a method for installing an apparatus for storing wafer carriers adjacent a processing tool, the method comprising:

providing an apparatus for storing wafer carriers comprising:

i) a frame adapted for floor-mounting and positionable adjacent a cleanroom wall, the frame comprising an extended portion configured so as to extend along the

cleanroom wall at an elevation below that of a docking station of a processing tool;

ii) a plurality of wafer carrier storage shelves supported by the frame and adapted to store wafer carriers, the plurality of shelves being aligned in a vertical column; and

iii) a wafer carrier mover supported by the frame and adapted to move wafer carriers along a path within a first plane containing the vertical column of shelves and a docking station of a processing tool;

positioning the extended portion of the frame adjacent an interface wall separating a processing tool from a cleanroom and at an elevation below an elevation of a docking station of the processing tool; and

positioning the frame such that the vertical column of shelves is aligned above the docking station of the processing tool.

45. The method of claim 44, wherein the step of providing an apparatus for storing wafer carriers comprising a frame adapted for floor-mounting and positionable adjacent a cleanroom wall, the frame comprising an extended portion configured so as to extend along the cleanroom wall at an elevation below that of a docking station of a processing tool comprises:

providing a floor-mountable portion of the frame that comprises the extended portion of the frame.

46. The method of claim 45, further comprising placing the floor-mountable portion of the frame on a floor of the cleanroom.

46. The method of claim 45, further comprising bolting the floor-mountable portion of the frame to the floor of the cleanroom.

47. The method of claim 43, further comprising securing the frame to the interface wall.

48. In a semiconductor device processing system, a method for transporting wafer carriers between a wafer carrier storage shelf of an apparatus for storing wafer carriers and a docking station of a processing tool, the method comprising:

providing an apparatus for storing wafer carriers comprising:

i) a frame adapted for floor-mounting and positionable adjacent a cleanroom wall, the frame comprising an extended portion configured so as to extend along the cleanroom wall at an elevation below that of a docking station of a processing tool;

ii) a plurality of wafer carrier storage shelves supported by the frame and adapted to store wafer carriers, the plurality of shelves being aligned in a vertical column;

iii) a vertical channel adjacent the vertical column of shelves adapted to permit movement of wafer carriers therealong; and

iv) a wafer carrier mover supported by the frame and adapted to move wafer carriers within a first plane containing the vertical column of shelves and the vertical channel;

positioning the frame adjacent an interface wall between a substrate processing tool and a cleanroom such that a docking station of the processing tool is positioned within the first plane and the extended portion of the frame

extends along the interface wall at an elevation below that of the docking station; and

causing the wafer carrier mover to move a wafer carrier between a shelf of the vertical column of shelves and the docking station within the first plane via the vertical channel.

49. The method of claim 48, wherein positioning the frame adjacent an interface wall between a substrate processing tool and a cleanroom such that a docking station of the processing tool is positioned within the first plane comprises:

positioning the frame such that the vertical column of shelves is aligned above the docking station of the processing tool.

50. The method of claim 48, wherein causing the wafer carrier mover to move a wafer carrier between a shelf of the vertical column of shelves and the docking station within the first plane via the vertical channel comprises:

causing the wafer carrier to move the wafer carrier horizontally away from the docking station to position the wafer carrier within the vertical channel, vertically through the vertical channel to position the wafer carrier adjacent the selected storage shelf and at an elevation above an elevation of the selected storage shelf, and horizontally to position the wafer carrier over the selected storage shelf.

51. An apparatus for storing wafer carriers, comprising:

a floor-mounted frame positionable on a cleanroom floor adjacent an interface wall separating a processing station from the cleanroom, the frame comprising a floor-

mounting portion configured so as to extend along the interface wall at an elevation below that of a docking station located adjacent a docking port through which the processing station may receive and discharge substrates from or to a wafer carrier disposed on the docking station, the frame being adapted to support wafer carriers within a vertically-oriented first plane within the cleanroom and adjacent the docking station;

a plurality of wafer carrier storage shelves supported by the frame and aligned in a vertical column above the docking station for storing wafer carriers within the first plane; and

a wafer carrier mover comprising an end effector adapted to engage a wafer carrier disposed within the first plane, the end effector being further adapted to carry the wafer carrier along a path contained within the first plane between a shelf of the plurality of wafer carrier storage shelves and the docking station, the wafer carrier mover being supported by the floor-mounted frame.

53. An apparatus for storing wafer carriers, comprising:

a frame adapted for floor-mounting and positionable on a cleanroom floor adjacent an interface wall separating a processing station from the cleanroom, the frame comprising a floor-mounting portion configured so as to extend along the interface wall at an elevation below that of a docking station, the frame further comprising a portion extending upward from the floor mounting portion and adapted to support a plurality of wafer carrier storage shelves within a vertically-oriented first plane within the cleanroom above the docking station;

a plurality of wafer carrier storage shelves supported by the frame comprising a first vertical column of

shelves and a second vertical column of shelves for storing wafer carriers within the first plane, and a vertical channel between the vertical columns so as to permit movement of wafer carriers therealong; and

a wafer carrier mover comprising an end effector adapted to engage a wafer carrier disposed within the first plane, the end effector being further adapted to carry the wafer carrier along the vertical channel between the vertical columns, the wafer carrier mover being supported by the frame.

53. A semiconductor device processing system, comprising:

a processing station to perform a fabrication step on a substrate;

a docking port through which the processing station is adapted to receive and discharge the substrate from or to a wafer carrier;

a docking platform adapted to support the wafer carrier adjacent the docking port;

a substrate transfer robot to transfer the substrate through the docking port; and

a wafer carrier storage apparatus located in the cleanroom, the wafer carrier storage apparatus including:

i) a frame adapted for floor mounting and positionable on a floor adjacent the processing station, the frame comprising a floor-mounting portion configured so as to extend laterally at an elevation below that of the docking platform;

ii) a plurality of wafer carrier storage shelves supported by the frame and aligned in a vertical column; and

iii) a wafer carrier mover adapted to carry a wafer carrier within a planar path between a shelf of the

plurality of wafer carrier storage shelves and the docking platform, the wafer carrier mover being supported by the floor-mounted frame.

54. The semiconductor device processing system of claim 53, further comprising a mechanism adapted to open a door of a wafer carrier disposed on and supported by the docking platform to provide horizontal access to a substrate stored within the wafer carrier.

REMARKS

Claims 1-3 and 5-21 have been cancelled in this paper without prejudice in order to further prosecution. Accordingly, while applicants maintain that the claims cancelled herein were not anticipated or rendered obvious by the prior art of record, Applicants herein present new claims 22-54 for consideration in view of the following remarks.

Certain features of the present invention provide patentability over the prior art of record, e.g., over Murata et al., Iwai et al., and Fosnight. Each such feature is recited in all of the independent claims 22, 43, 48, 51, 52 and 53 and is fully supported in the as-filed specification (corresponding page, line number, and figure citations are provided). For example, the frame may be positioned adjacent a cleanroom wall (page 5, lines 26-27 and FIG. 1) and/or adjacent a processing station/tool (page 3, line 31 through page 4, line 6, and FIG. 1). As another example, the frame may be adapted for floor mounting (page 5, line 26 and FIG. 3) and/or comprise a floor-mounting portion (page 5, line 26 and FIG. 3) (e.g., in one or more embodiments the frame may be placed on and/or be bolted to the floor of a cleanroom (page 5, line 26, FIG. 3)). As a

further example, the floor-mounting portion of the frame and/or an extended portion of the floor-mountable frame is configured to extend along the wall of the cleanroom and/or laterally at an elevation below that of a docking station of a processing station/tool (page 5, lines 27-29 and FIG. 3).

Applicants urge that each of the new independent claims recite structural limitations to the term "frame" (e.g., floor-mountable, floor-mounting portion, extended portion, extending along a wall of the cleanroom and/or laterally, positionable adjacent a cleanroom wall and/or a processing station). As such, Murata et al. and Iwai et al., considered by the Examiner to comprise a "frame", broadly stated, are positively distinguished by structural limitations, as implicitly requested by the Examiner in relevant claim rejections lodged in the June 13, 2002 Office Action and affirmed in the December 5, 2002 Final Office Action.

Further, applicants have also carefully considered Examiner's observation stated in the December 5, 2002 Final Office Action, that "[n]othing precludes a frame from being comprised of multiple components." In response, applicants assert that, at least because of the presence of the three separable limitations noted above (e.g., the floor-mountable aspect, the adjacent-positioning aspect, and the extending aspect relative to a docking station of a higher elevation) in all of the new independent claims in one form or another, each such claim is clearly distinguished over all prior art of record in the present case, including Fosnight. Prompt notice of allowance for the same is hereby respectfully solicited.

Applicants further note that the new dependent claims also recite limitations providing strong distinguishing power over the prior art of record. For

example, dependent claim 23 requires that a floor-mounting portion of the frame be configured so as to "substantially fit below the docking station" (page 5, lines 27-29 and FIG. 3), a limitation not taught or suggested in any of Iwai et al., Murata et al., or Fosnight, and, further, which would not likely have occurred to or seemed useful to Fosnight, who focused on storing and moving wafer cassettes via extended framing members positioned solely in the overhead above docking stations, and who therefore employed wall- or ceiling-mounted wafer carrier moving and apparently ceiling-mounted storage shelves. Also, claim 24 requires "at least one vertically-extending post extending upward from the floor-mounting portion" for supporting the storage shelves, an element not taught or suggested in any of Iwai et al., Murata et al., or Fosnight. Further, claim 29 requires that the "floor-mounting portion of the frame" includes "a horizontally-extending frame member" that extends "outward away from the interface wall" and defines a "depth of the frame," another element not taught or suggested by any of the three present references (e.g., at least insofar as such a frame member comprises a part of the floor-mounting portion).

Please charge deposit account No. 04-1696 in the amount of $402.00 to cover the fees for the additional 13 claims in excess of 20 and the additional 2 independent claims not previously paid for. Applicants do not believe any other fees are due regarding this amendment. If any additional fees are required, however, please charge Deposit Account No. 04-1696. Applicants encourage the Examiner to

telephone Applicants' attorney to discuss the amendment should any issues remain.

Respectfully submitted,

Brian M. Dugan, Esq.
Registration No. 41,720
Dugan & Dugan, LLP
Attorneys for Applicants
(914) 332-9081

Dated: June 5, 2003
Tarrytown, New York

TRANSMISSION VERIFICATION REPOR

TIME : 06/05/2003 23:34
NAME : DUGAN & DUGAN
FAX : 9143329082
TEL : 9143329081

DATE,TIME	06/05 23:27
FAX NO./NAME	17033057687
DURATION	00:07:14
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